



Docket No. 1076.1063

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Yuuichi TACHINO et al.

Serial No. 09/775,653

Group Art Unit: 1763

Confirmation No. 9294

Filed: February 5, 2001

Examiner: Anna M. Crowell

For: PLASMA ETCHING METHOD AND APPARATUS

AMENDMENT FILED SIMULTANEOUSLY WITH RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is responsive to the final Office Action mailed June 30, 2004, having a shortened period for response set to expire on September 30, 2004. A petition and fee for a THREE-month Extension of Time is enclosed, thereby extending the response period to December 30, 2004.

The following amendments and remarks are respectfully submitted.

01/03/2005 HALI11 00000003 09775653

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